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## BIB DATA SHEET

CONFIRMATION NO. 8085

SERIAL NUMBER	FILING or 371(c) DATE	CLASS	GROUP ART UNIT	ATTORNEY DOCKET NO.	
10/549,294	09/16/2005	451	3727	278426US0PCT	
<b>RULE</b>					
<b>APPLICANTS</b> Mitsugu Abe, Atsugi-shi, JAPAN; Nobuyoshi Nambu, Yokkaichi-shi, JAPAN; Osamu Ito, Yokkaichi-shi, JAPAN; Masaaki Ogitsu, Tsukuba-shi, JAPAN; Kazuo Inomata, Tokyo, JAPAN;					
<b>** CONTINUING DATA *****</b> This application is a 371 of PCT/JP04/03642 03/18/2004					
<b>** FOREIGN APPLICATIONS *****</b> JAPAN 2003-074581 03/18/2003					
<b>** IF REQUIRED, FOREIGN FILING LICENSE GRANTED **</b> 06/04/2006					
Foreign Priority claimed <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No 35 USC 119(a-d) conditions met <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No Verified and /ROBERT A ROSE/ Acknowledged Examiner's signature	<input type="checkbox"/> Met after Allowance Indicate	<b>STATE OR COUNTRY</b> JAPAN	<b>SHEETS DRAWINGS</b> 6	<b>TOTAL CLAIMS</b> 14	<b>INDEPENDENT CLAIMS</b> 2
<b>ADDRESS</b> OBLON, SPIVAK, MCCLELLAND MAIER & NEUSTADT, L.L.P. 1940 DUKE STREET ALEXANDRIA, VA 22314 UNITED STATES					
<b>TITLE</b> Material for purification of semiconductor polishing slurry, module for purification of semiconductor polishing slurry and process for producing semiconductor polishing slurry					
<b>FILING FEE RECEIVED</b> 1460	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:			<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit	